



# WPI-AIMR and Fraunhofer ENAS Joint Workshop on Micro Integrated Devices

Date: 2013/02/22 Friday

Place: Aoba Memorial Hall 4th floor (Aobayama Campus, Tohoku University)

(<http://www.eng.tohoku.ac.jp/map/?menu=campus&area=c&build=03>)

10:00 – 10:10	<b>Opening Remarks</b> Director Prof. Motoko Kotani (WPI-AIMR)
<b>NEMS/MEMS and nanomaterial-enhanced passive components ( JST-DFG Cooperative Program )</b>	
10:10 – 10:30	<b>Heterogeneous integration of MEMS and LSI using adhesive bonding</b> Prof. Masayoshi Esashi (WPI-AIMR) and Prof. Shuji Tanaka ( Graduate School of Engineering, Tohoku University)
10:30 – 11:00	<b>Smart Systems Integration by using Micro- and Nanotechnologies</b> Prof. Thomas Gessner (Fraunhofer ENAS, Chemnitz University of Technology, WPI-AIMR)
11:00 – 11:25	<b>Nanomaterial integrated three dimensional inductors</b> Dr. Yu-Ching Lin (WPI-AIMR)
11:25 – 11:50	<b>Functional liquids within NEMS/MEMS fabrication</b> Mr. Felix Gabler (Fraunhofer ENAS, Chemnitz University of Technology)
11:50 – 12:15	<b>Wafer level bonding of heterogeneous substrates at low temperature</b> Mr. Jörg Frömel (Fraunhofer ENAS, Chemnitz University of Technology, Fraunhofer Project Center at Tohoku University)
Lunch break	
<b>Functional material integration</b>	
13:30 – 14:00	<b>[Special Speech] Dealloyed nanoporous metals for device applications</b> Prof. Mingwei Chen (WPI-AIMR)
14:00 – 14:30	<b>[Guest Speech] Piezoelectric MEMS mirror with wide scan angle actuated by Nb doped PZT film</b> Mr. Takayuki Naono (Fujifilm Corporation)
14:30 – 14:50	<b>MEMS switch using metallic glass thin film</b> Mr. Yu-Lang Chu ( Fraunhofer ENAS)
14:50 – 15:10	<b>Integration and fabrication of magnetic metallic glass for MEMS mirco-mirror system</b> Dr. Yao-Chuan Tsai (WPI-AIMR)
15:10 – 15:30	<b>Fabrication of L10FePt based patterned recording media</b> Dr. Neelam Kaushik (WPI-AIMR)
Coffee break	
<b>Micro devices and fabrication</b>	
15:45 – 16:15	<b>[Guest Speech] MEMS Technology challenges for RF-MEMS devices</b> Dr. Koichi Ikeda (Sony Corporation)
16:15 – 16:35	<b>Integrated Tactile Sensor Device</b> Dr. Masanori Muroyama (WPI-AIMR)
16:35 – 16:55	<b>Local redox cycling-based electrochemical chip device for high-throughput cell analysis</b> Dr. Kosuke Ino (Graduate School of Environmental Studies, Tohoku University)
16:55 – 17:15	<b>Microscale technologies to fabricate muscle tissues</b> Dr. Samad Ahadian (WPI-AIMR)
17:15	<b>Closing Address</b> Prof. Masayoshi Esashi
Closing	
18:00 – 20:00	Reception

Language: English | Admission Free | Registration Required for Reception (5000 Yen) by 2013.2.8

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